

AMENDMENTS TO THE CLAIMS

Claims 1-18 (Cancelled)

19. (Currently Amended) A stamper for embossing at least one pattern of recesses in a surface of a substrate for a magnetic recording medium, said substrate surface including spaced-apart landing and data zones, said stamper comprising:

- (a) a main body including a surface; and
- (b) means for embossing a pattern of ~~rectangularly-shaped or~~ sinusoidally-shaped recesses in said landing zone of said substrate surface.

20. (Original) The stamper as in claim 19, further comprising:

- (c) means for simultaneously embossing a servo pattern in said data zone of said substrate surface.

21. (Currently Amended) A stamper for embossing at least one pattern of recesses in a surface of a substrate for a magnetic recording medium, the stamper comprising:

a stamping surface including a pattern of ~~rectangularly-shaped or~~ sinusoidally-shaped protrusions,

wherein said pattern of ~~rectangularly-shaped or~~ sinusoidally-shaped protrusions is a negative image of the pattern of recesses to be embossed in the surface of the substrate.

22. (Previously Presented) The stamper according to claim 21, wherein said stamping surface comprises a metal or metal alloy.

23. (Previously Presented) The stamper according to claim 22, wherein the metal is selected from Al or Al/NiP.

24. (Previously Presented) The stamper according to claim 22, wherein the metal alloy is Al-Mg.

25. (Withdrawn) The stamper according to claim 21, wherein said stamping surface comprises a hydrophobic polymer.

26. (New) The stamper according to claim 21, wherein said pattern of sinusoidally-shaped protrusions comprises a plurality of spaced apart peaks and valleys, wherein a peak-to-peak spacing of adjacent peaks is in the range from about 0.1 to about 10 μm and a depth of each valley is in the range from about 10 to about 200 \AA .